



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

2877
#9/105
7/6/00

Applicants: Heaton, John D.; Spady, Blaine R.
Assignee: Nanometrics Incorporated
Title: Metrology/Inspection Positioning System
Serial No.: 09/458,123 Filing Date:
Examiner: Unknown Group Art Unit: 2877
Docket No.: M-7677 US

San Jose, California
June 27, 2000

ASSISTANT COMMISSIONER FOR PATENTS
Washington, D. C. 20231

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made, other than as described above; or

LAW OFFICES OF
SKJERVEN, MORRILL,
ACPERSON, FRANKLIN
& FRIEL LLP

25 METRO DRIVE
SUITE 700
SAN JOSE, CA 95110
(408) 453-9200
FAX (408) 453-7979

RECEIVED
JUL -3 2000
TO 2877 MAIL ROOM

3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).



I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on June 27, 2000.

David Miller 6-27-00
Attorney for Applicants Date of Signature

Respectfully submitted,

David Miller

David T. Millers
Attorney for Applicants
Reg. No. 37,396

LAW OFFICES OF
SKJERVEN, MORRILL,
ACPERSON, FRANKLIN
& FRIEL LLP

25 METRO DRIVE
SUITE 700
SAN JOSE, CA 95110
(408) 453-9200
FAX (408) 453-7979